



제25회 한국반도체학술대회

The 25th Korean Conference on Semiconductors

2018년 2월 5일(월)-7일(수), 강원도 하이원리조트 컨벤션 호텔

2018년 2월 7일(수), 09:00-10:30

Room K (육백II, 6층)

Q. Metrology, Inspection, and Yield Enhancement 분과

[WK1-Q] Inspection & Yield Enhancement

좌장: 양준모 박사(나노종합기술원)

<p>WK1-Q-1 09:00-09:15</p>	<p>Development of UV Line Scanning System for Detecting Wafer Defect of XXnm Size Han Gyeong Oh¹, Han Mo Yang¹, Seong Chul Oh², Seung Yong Chu², and Jai Soon Kim¹ <i>¹NEMO Lab, Department of Physics, Myongji University, ²AUROS Technology</i></p>
<p>WK1-Q-2 09:15-09:45</p>	<p>[초청] Micro-Thermography and Applications Ki Soo Chang¹, Dong Uk Kim¹, Byung-Seon Chun² <i>¹Division of Scientific Instrumentation, Korea Basic Science Institute, ²Nanoscope Systems, Inc.</i></p>
<p>WK1-Q-3 09:45-10:00</p>	<p>Design of the Hi-Efficiency Dark-Field Illumination System Using Anamorphic Optics for Near-Field Microscope Sunseok Yang¹, Woojun Han¹, Seungyoung Chu², Seungchul Oh², Jaisoon Kim¹ <i>¹Department of Physics, Myongji University, ²AUROS technology</i></p>
<p>WK1-Q-4 10:00-10:15</p>	<p>Early Yield Ramping Up Methodology through Multi-Layers Simulation with Real Process Variation Jin Kim, Byung-Moo Kim, JunSu Jeon, Ki-Heung Park, Jae Hyun Kang, SeungWeon Paek, and ByungMoo Song <i>Technology Development, Foundry, Samsung Electronics</i></p>
<p>WK1-Q-5 10:15-10:30</p>	<p>Yield 개선을 위한 Wafer Edge Weak Point 개선 System 구축 산포분석에 의한 검증과 2Defect Library System 의 활용 Hyunwoo Kang, Sangwoo Kim, Sunkeun Ji, Sookyeong Jeong, Minwoo Park, Hun Lee, Jungchan Kim, Cheolkyun Kim, Hyunjo Yang <i>R&D Division, SK Hynix</i></p>